



TSMC-03-267

February 27, 2004

To: Commissioner for Patents
P.O.Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/729,458 12/05/03 |
Yi Song Chiu et al.
NOVEL MULTI-GATE FORMATION PROCEDURE
FOR GATE OXIDE QUALITY IMPROVEMENT
| _____ |

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service as first class
mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450, on March 1, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

SBA 3/1/04

U.S. Patent 5,858,106 to Ohmi et al., "Cleaning Method for Peeling and Removing Photoresist," discloses a cleaning method for peeling and removing photoresists from a semiconductor by applying ultrasound to a cleaning solution.

U.S. Patent 5,454,901 to Tsuji, "Process for Treating Semiconductor Substrates," discusses a process which can show an excellent effect of removing metallic impurities and reduce deposit of microparticles.

U.S. Patent 6,513,538 to Chung et al., "Method of Removing Contaminants from Integrated Circuit Substrates Using Cleaning Solutions," discloses a method for removing contaminants from a integrated circuit substrate.

Sincerely,

A handwritten signature in black ink, appearing to read 'SBA', with a long horizontal flourish extending to the right.

Stephen B. Ackerman,
Reg. No. 37761

(Use several shouts if necessary)

Aggregation Number

10 | 729,458

Yi Song Chiu et al.

12/05/03

Group Art Unit

PTO-1
TYPE
INFO
MAR 03 2004
PATENT & TRADEMARK OFFICE

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Portion or Pages, Etc.)

[illegible]

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.